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## Conformal and highly adsorptive metal—organic framework thin films *via* layer-by-layer growth on ALD-coated fiber mats

Electronic Supplementary Information

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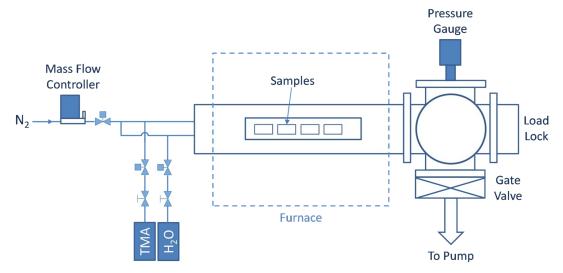


Figure S1. Schematic of the homemade hot-wall viscous-flow ALD reactor used for ALD  $Al_2O_3$  coatings on fibers. In an ALD cycle, trimethylaluminum (TMA) and water are dosed sequentially into the chamber, with a purge step of inert gas  $(N_2)$  in between. Deposition temperature is controlled by the furnace, and all the gas lines and valves are wrapped with heating tapes to prevent precursor condensation.